

International Journal of Mass Spectrometry 215 (2002) 1-12



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# An MCP-based detector array with integrated electronics

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Received 26 June 2001; accepted 19 November 2001

#### **Abstract**

Various position sensitive readout systems for microchannel plates are considered. A discrete anode detector with 192 channels and integrated data acquisition electronics developed at the University of Wales, Aberystwyth is presented. Details of the custom silicon circuit which performs data acquisition in the device are given, together with key performance indicators. An example application of the detector enhancing the performance of a GCMS measurement is given. The next generation of detector currently under development is briefly introduced. (Int J Mass Spectrom 215 (2002) 1–12) © 2002 Elsevier Science B.V. All rights reserved.

Keywords: Microchannel plate; Multi-anode; Array detector

# 1. Introduction

The microchannel plate (MCP) is a versatile and powerful detector for ions, electrons, and photons with energies ranging from UV to X-ray [1]. The impact of an ion, electron or photon on the front face of the MCP gives rise to secondary electrons inside the body of the MCP which results in an avalanche multiplication process leading to a pulse of up to  $10^7$  electrons emerging from the rear face of the MCP. By the use of a suitable collection system for these electrons, the position of the original impact on the front surface of the MCP may be determined to within a few microns.

The methods of determining the position of ion impact fall into three basic categories: discrete anode and coincidence arrays [2–11]; charge division [12–25]; and optical imaging detectors [26–34]. As will be seen,

each of these detection techniques makes a different trade-off in terms of performance, component count and complexity.

# 1.1. Charge division detectors

Position sensitive detectors based on charge division techniques give a continuous variation in output depending on the position of the event. Charge division detectors fall into three categories: resistive anode and capacitive charge division, [13,14,19,20,23,25,35]; delay line techniques [22,26,36–40]; and shaped anodes [21,41–44].

They have the advantage of low component count, requiring only two sets of electronics for a 1-dimensional detector (1D) and four sets for a 2-dimensional detector. Against this, they suffer from the limitation in maximum count rate that they can only cope with single events occurring within the time frame of the detector electronics.

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# 1.2. Discrete multi-anode detectors

Multi-anode detectors are conceptually the simplest imaging devices employed with MCPs. An array of anodes is placed within proximity focus of the rear face of the MCP stack in vacuum or is deposited directly on the rear face of the MCP [3–5,7,8,45–48]. Each anode is connected to an electronics channel comprising a charge sensitive amplifier, discriminator and counter.

The spatial resolution of the detector is limited only by the size of the spacing of the anodes (assuming this is greater than the pore spacing of the MCP). High count rates are achievable, limited only by the performance of the MCP.

Conventional multi-anode arrays suffer from the disadvantage of requiring a large number of electronic components due to the discrete electronics required for each anode and also from cross talk between the anodes [49]. Stray capacitances on each channel are of the order of 10 pF with a cross coupling capacitance of 0.5 pF between adjacent channels, resulting in peak signals of the order of 20 mV with 1 mV of cross coupled signal appearing on adjacent electrodes. In conventional multi-anode arrays, the channel-to-channel crosstalk is the limiting factor in the performance of the detector. In addition to the performance limits imposed by stray capacitance, the multi-way feedthrough needed to connect the detector in the vacuum system to the external electronics system is a problematic and expensive component.

# 1.3. Coincidence arrays

Coincidence arrays are an attempt to reduce the component count inherent in multi-anode detectors by connecting the anodes to the amplifiers in such a way as the position of the event is encoded by simultaneous pulses from two amplifiers.

The performance cost of this reduction in component count is manifested in a reduction in the maximum count rate that the detector can cope with. The detector responds badly to the case of two events

occurring within the time resolution of the amplifiers and coincidence detector, effectively giving a random position for one event occurring. Thus, the maximum count rate for the coincidence detector will be determined by the time required for the electronics to decode and output the position of the event and reset itself ready for the next event.

At high count rates the random events caused by pulse 'pile-up' will manifest themselves as noise spread across the array, thus, a coincidence detector has a low 'intra-specular' dynamic range, despite achieving a respectable dynamic range for single peaks.

# 1.4. Integrated multi-anode devices

By integrating the charge amplifier and discriminator circuits onto a piece of silicon together with the collection anodes, the problems associated with crosstalk can be greatly reduced in a multi-anode detector. By putting some of the data acquisition electronics in the vacuum system, right alongside the MCP, it is possible to arrange such that only low impedance logic level signals have to pass through the vacuum envelope. Additionally, by accumulating counts in the data acquisition device, the feedthrough requirements may be greatly reduced. The other advantage of an integrated device is that the high component count traditionally associated with multi-anode devices is greatly reduced, the Aberystwyth detector contains approximately 64,000 devices on a single piece of silicon measuring approximately  $5 \text{ mm} \times 15 \text{ mm}$ .

One such device is due to Hicks and Hatfield (UMIST, UK) [50] and Hatfield et al. [51]. This has up to 29 channels on a pitch of  $160\,\mu m$  and has been fabricated and tested in a number of applications.

The detector presented here is an integrated multi-anode device and differs from the Hicks and Hatfield detector in several important respects, notably in that this detector has 192 channels on a pitch of  $25\,\mu m$ . In addition, the sensor circuits used on this device are self resetting [52], requiring no global clocks, which simplifies control of the array.

#### 2. The Aberystwyth detector

The Aberystwyth charge sensitive detector array comprises a number of custom silicon integrated circuits mounted on a ceramic substrate in proximity to the rear face of an MCP. Each detector chip contains 192 channels, or pixels, on a pitch of  $25\,\mu m$ . Each channel has a metal anode to collect the electrons as they emerge from the MCP; a charge sensitive amplifier to produce a digital signal in response to the electron pulse and an 8-bit counter associated with it to accumulate the counts as they arrive and circuitry to read out the data sequentially from all channels in the

array. The spacing of the anodes was chosen to fit in with the geometry of a typical mass spectrometer having a minimum source slit width of 25 µm and a magnification close to unity. The collection anodes are furnished with a secondary electrode allowing charge to be injected from an external source, this is invaluable in allowing the circuit to be tested once silicon fabrication is complete so that good devices may be selected for assembly into the detector modules. A floorplan of the device is shown in Fig. 1, showing the layout of the principal components and their relative sizes.

The silicon detector chip was fabricated on a 3 µm CMOS process by Hughes Microelectronics

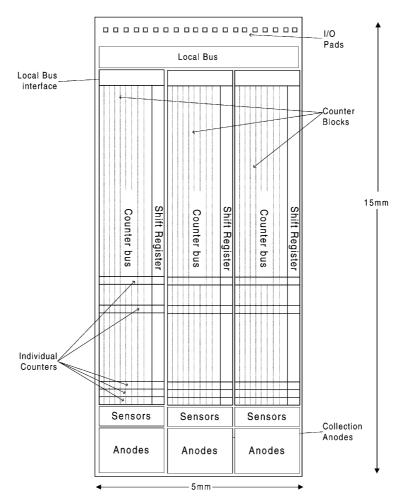


Fig. 1. Floorplan of array detector circuit.

Europa Ltd. In order to reduce the stray capacitance associated with the collection anodes, a special processing step was specified in the CMOS process where the normal dielectric layer underneath the uppermost metal layer in the circuit was replaced with a thick layer of polyimide material, this reduced the capacitance of each anode to approximately 0.2 pF, with a cross coupling capacitance of 0.003 pF. The low value of anode capacitance and even lower cross coupling capacitance results in a large signal presenting itself at the input to the on-chip charge sensitive amplifier. Simulations predict that a voltage pulse of about 0.1 V will result from 10<sup>5</sup> electrons emerging from the MCP and landing on the collection anode.

An important feature of any MCP readout device is its ability to withstand transients appearing on the input. The MCP is an avalanche device and it is possible for output pulses much larger than normal to be produced, particularly during initial run-up of the MCP. The input circuits on the Aberystwyth detector have been designed with protection devices such that excess charge on the collection anode is conducted away to ground, before it can damage the sensitive circuitry of the charge sensitive amplifier.

The circuit has been designed such that an arbitrary number of detector chips may be abutted together on a substrate behind the MCP, allowing for long focal plane detectors to be built, limited only by the size of MCPs available (currently approximately 100 mm). The output from the counters on the detectors is presented via an 8-bit port and is read into a PC by means of a simple interface based around the 8255 Peripheral Interface Adapter circuit. A number of detectors have been built and tested in a number of different instruments. A summary of results obtained is presented here.

# 2.1. Peak shape and spatial resolution

Initial in vacuuo testing of the device was done in a VG/Micromass Autospec mass spectrometer, using the background residual gas in the machine. The detector was positioned at approximate location of the focal plane of the instrument, behind the conversion dynode of the existing photomultiplier detector in the machine as shown in Fig. 2. When the machine is used with the conventional photomultiplier detector, the conversion dynode is at a potential of  $-40 \,\mathrm{kV}$ , ions passing through the collector slit are accelerated onto the aluminium surface of the dynode and cause secondary electrons to be liberated. These secondary electrons impinge upon the scintillator where photons are created which travel down the light guide to be converted back to an electrical signal and amplified by an avalanche photomultiplier. When the conversion dynode potential is removed, the incoming ions impinge

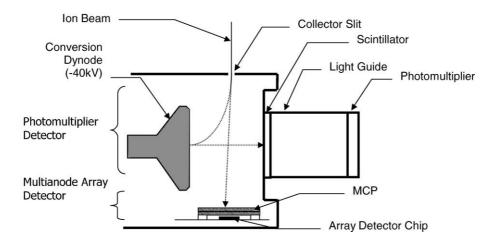


Fig. 2. Mounting the array detector with the existing photomultiplier.

#### Response of array to peak at Mass 32 (O<sub>2</sub><sup>+</sup>) VMCP=1800V

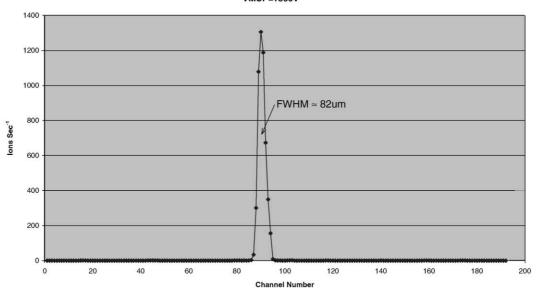


Fig. 3. Image of peak at mass 32.

upon the front face of the MCP and are detected by the array detector. Positioning the detector in such a way enabled the beam to be switched between the two detectors simply by switching the supply to the conversion dynode. A deflection lens assembly (not shown in diagram) is positioned in front of the MCP allowed the incoming beam of ions to be steered across the array independently of the ion optics of the rest of the instrument. The machine was aligned and optimized using the photomultiplier before switching the beam onto the array detector, when the peak in Fig. 3 was obtained. The peak shown is at mass 32 and corresponds to  $^{16}\text{O}_2^+$ . The full-width half-maxima (FWHM) of a number of peaks were measured and the average found to be  $82~\mu\text{m}$  or just over three detector channels.

# 2.2. Noise floor and maximum count rate

By turning off the ion source in the instrument, it is possible to determine the dark count rate, or noise floor of the detector. This was measured and found to be approximately  $3 \times 10^{-4}$  counts per second per chan-

nel. By turning off the MCP supply potential, it was confirmed that all of this noise was arising in the MCP.

By using the array detector in the configuration with the existing photomultiplier-based detector, it is possible to determine the linearity of the array detector and in particular the maximum count rate that maybe obtained from it. Three peaks of widely differing amplitudes were located in the residual background atmosphere of the instrument. These peaks arise from the oil used in the diffusion pumps of the instrument and can be expected to remain constant over a long period of time. The amplitudes of these peaks were recorded on both the photomultiplier and the array detector as their amplitudes were varied over a wide range by adjusting the ion source of the instrument. The result is shown in Fig. 4, where the measurement points are plotted alongside a curve giving the theoretical response of a paralyzable counter [53]. In this case, the modified count rate of the counter is given by the equation

$$\lambda' = \lambda \, e^{-\lambda \tau}$$

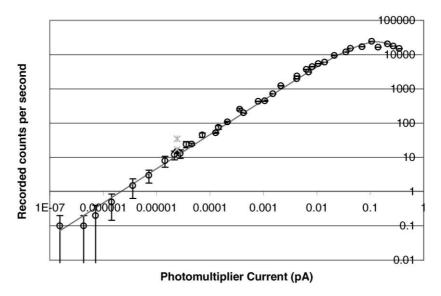


Fig. 4. Comparison of array detector with photomultiplier.

where  $\lambda'$  is the modified count rate,  $\lambda$  the original count rate and  $\tau$  the dead-time of the detector. By fitting this theoretical curve to the observed data, it was found that the value of  $\tau$  and hence the dead time of each channel is approximately  $16\,\mu s$ . It should be noted that this dead-time is due to the MCP and agrees closely with the quoted maximum count rate for the MCP adjusted for the area of one of the collection anodes. Combining this result with the dark noise result gives an ion counting detector which is linear over approximately seven orders of magnitude, limited at each end of its performance scale by current MCP technology.

# 2.3. Comparison with other detectors

The performance of the Aberystwyth Integrated Multianode detector is compared with examples of MCP readout systems in Table 1. It can be seen that the performance attained by the Aberystwyth detector equals or surpasses that of other readout systems, particularly as regards to the dynamic range of the system, where the MCP becomes the limiting factor in performance.

# 3. Applications

The versatility and range of uses of this detector are very broad indeed. As was seen above, the dynamic range of the device is limited only by the current state of microchannel plate performance and other features of the detector give it unique benefits when used in several application areas. This section illustrates the benefits offered by the detector by showing how the imaging ability of the detector enables differentiation between different elutants from a gas chromatography mass spectrometry (GCMS) analysis [56].

In applications where gas chromatography is combined with mass spectrometry (GCMS), there is a requirement for high sensitivity detection combined with high resolution. This is particularly true in the case of trace analysis of environmental contaminants, such as polychlorinated dioxins, furans and biphenyls, and also in the detection of drugs of abuse and performance enhancing substances in sport. In these applications the only available technique for analysis is a mode of operation known as selective ion recording (SIR). In the SIR technique, the mass spectrometer is

Table 1 Comparison of different MCP-based detectors

Detector type	Reference	Spatial	Number of	Maximum	Maximum	Dynamic	Notes
		resolution (μm)	channels	count rate (channel)	count rate (array)	range	
		(μπ)		counts	counts		
				$second^{-1}$	$second^{-1}$		
Aberystwyth (integrated multianode)		25	192 per chip	$10^{4a}$	$4 \times 10^{6}$	>10 <sup>5</sup>	2-Chip module demonstrated (384 channels)
Other Integrated multianode	[54]	160	32 per chip				4-Chip module demonstrated (128 channels)
Discrete multianode	[2]	50	96	$10^{4a}$	$10^{6}$		High component count for readout
							Performance limited by cross coupling
Coincidence array (MAMA)	[55]	25	1024	$2 \times 10^{3}$	$2 \times 10^6$	100	Pulse pile-up at high count rates limits
							dynamic range
Charge division (resitive	[12,13]	400	64	$10^{4}$	$7 \times 10^5$	$10^{4}$	Resolution limited by noise pulse pile-up at
anode/capacitive division/coded anode)							high count rates causes ghosting
Optical imaging (photodiode)	[30]	25	1024	$5 \times 10^5$	$1 \times 10^7$	500	Not pulse counting at high rates

<sup>&</sup>lt;sup>a</sup> Count rate limited by MCP.

set to record ions from one mass at a time, rather than scanning a spectrum from a range of masses across a single point detector. In this way, the detector may operate at maximum sensitivity, however, the technique is susceptible to interferences caused by contributions from peaks of similar mass to the measured peak entering the detector.

In order to confirm the presence of these interferences, it is possible in some cases, to switch between two or more ions and perform isotope ratio measurements on these. However, in cases where interference is suspected, there is often no information in the SIR data to determine the extent or cause of the interference. Mass profile scanning [57], which employs a series of short scans across the width of the peak, can provide more information about possible interferences, but at a loss of sensitivity.

A typical SIR chromatogram obtained from a sample of a doping control standard at mass 448.3192 Da is shown in Fig. 5. This chromatogram was obtained

using the existing photomultiplier fitted to the machine and the mass determined by using the standard machine calibrations and operating conditions. Of particular interest were the peaks in the magnified area (4 and 6), which were thought to be due to interference arising from side lobes of peaks of ions near to the target mass.

A routine was written for the detector array control program which would repeatedly take samples from the array, storing each sample onto disk together with the value of the PCs real time clock at the time of the sample, allowing a sequence of spectra taken over time to be accumulated.

The experiment was repeated using the detector array with the control program set to take a series of readings over a period of several minutes. Once the readings had been taken, the results were plotted as a 3D plot as shown in Fig. 6. In this plot, time is plotted along the *x*-axis, the mass of the ion is plotted along the *y*-axis into the page and the number of counts

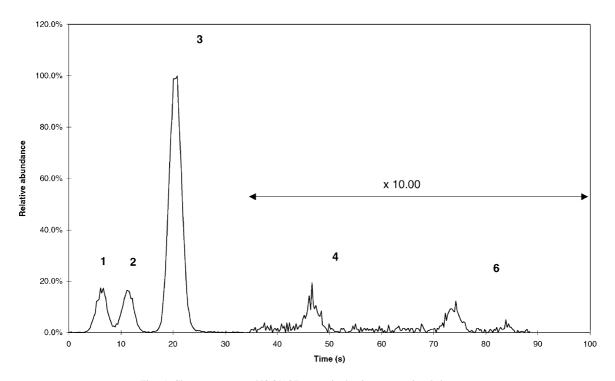


Fig. 5. Chromatogram at 448.3192 Da acquired using conventional detector.

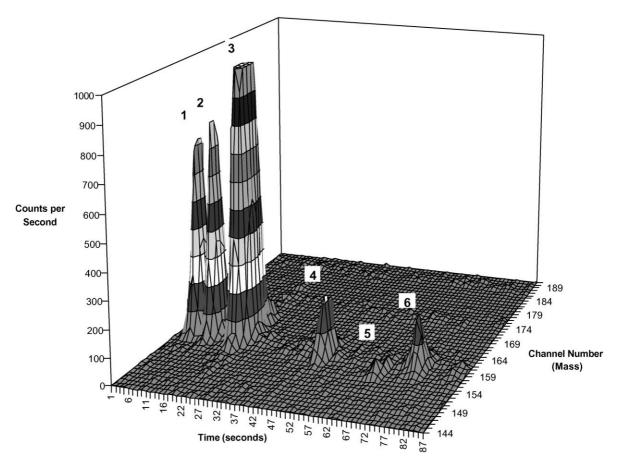


Fig. 6. Chromatogram at 448.3192 Da acquired using array detector.

plotted on the *z*-axis. Although the array detector has not been accurately calibrated to allow conversion from channel number to mass, rough calculations show that under these conditions, the mass calibration is approximately 0.001 Da per channel.

By viewing the 3D plot from above, a contour plot is formed as shown in Fig. 7, the presence of the interference peaks (4–6) may be readily confirmed. By observing the peaks (not shown on plots) due to the carrier gas in the GC column, which remain constant over time, it was possible to confirm that the shift in center of mass of peaks 4–6 was indeed due to interference from unwanted species rather than machine drift.

# 4. Conclusions and further directions

The detector presented here represents a major advance on the performance attainable from other MCP readout techniques. The integration of the first stage of data acquisition circuitry alongside the collection anodes, inside the vacuum system, offers many advantages in terms of both detector performance and also system integration. The silicon integrated circuits containing the data acquisition circuitry have proved to be vacuum compatible, work is currently being carried out on an electron spectrometry application where a detector module has been pumped to  $10^{-9}$  Torr and 'sniffed' with a mass spectrometer

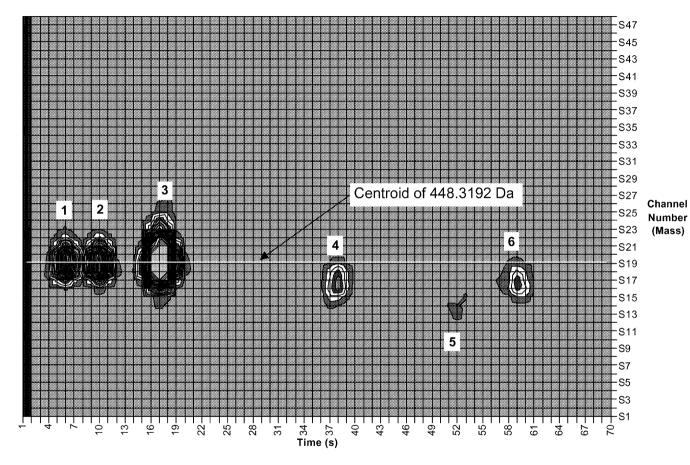


Fig. 7. Contour plot of chromatogram at 448.3192 Da.

head which revealed no serious outgassing. The circuit has also proved electrically robust, withstanding both normal operation and a number of flashover type incidents within the MCP stack. Further work is planned to determine the ESD tolerance of the device.

Work is progressing on the design and construction of the next generation of detector devices at Aberystwyth. Although the project is specifically aimed at electron energy spectrometry, the detector will also find application in mass spectrometry and other fields. Advances in silicon fabrication have shrunk the feature size attainable and a process with a gate length of 0.5 µm is now readily available, compared with the gate length of 3 µm used in the device presented here. The smaller feature sizes attainable will result in a device with higher sensitivity to electrons, allowing the MCP to be operated at a lower potential resulting in less spreading of the peak. In addition, as the devices within the charge sensitive amplifiers are proportionately larger compared with the minimum possible, there should be greater uniformity from channel to channel across the device. Test structures for this process are being fabricated at the time of going to press and offer the possibility of improved uniformity across the array and the fabrication of detector circuits with more pixels.

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